



## SDI Review Form 1.6

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|--------------------------|--|
| Journal Name:            | <a href="#">Physical Science International Journal</a>   |
| Manuscript Number:       | Ms_PSIJ_33788  |
| Title of the Manuscript: | Deposition of Silicon Films from Liquid Cyclopentasilane Precursors Using High Pressure Spray System |
| Type of the Article      |  |

### **General guideline for Peer Review process:**

This journal's peer review policy states that **NO** manuscript should be rejected only on the basis of '**lack of Novelty**', provided the manuscript is scientifically robust and technically sound.

To know the complete guideline for Peer Review process, reviewers are requested to visit this link:

(<http://www.sciencedomain.org/page.php?id=sdi-general-editorial-policy#Peer-Review-Guideline>)

### **PART 1: Review Comments**

|  | Reviewer's comment   | Author's comment (if agreed with reviewer, correct the manuscript and highlight that part in the manuscript. It is mandatory that authors should write his/her feedback here) |
|--|--|---|
| <b><u>Compulsory</u></b> REVISION comments | Update references to current article. Most of those given are too old to be trusted with current trends in research. |   |
| <b><u>Minor</u></b> REVISION comments      | Reference should be in italics and <i>et al.</i> not et al.  |   |
| <b><u>Optional/General</u></b> comments    | It's a good paper but needs minor corrections.   |   |

### **Reviewer Details:**

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|----------------------------------|---|
| Name:                            | <b>Cliff Orori Mosiori</b>                    |
| Department, University & Country | <b>Technical University of Mombasa, Kenya</b> |